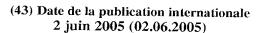
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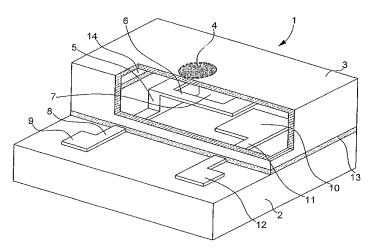
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[Suite sur la page suivante]

(54) Title: METHOD FOR CONTROLLING THE HERMETICITY OF A CLOSED CAVITY OF A MICROMETRIC COMPONENT, AND MICROMETRIC COMPONENT FOR THE IMPLEMENTATION THEREOF

(54) Titre : PROCEDE DE CONTROLE DE L'HERMETICITE D'UNE CAVITE CLOSE D'UN COMPOSANT MICROMETRIQUE, ET COMPOSANT MICROMETRIQUE POUR SA MISE EN OEUVRE



(57) Abstract: For the method for controlling the hermeticity of a closed cavity (14) of at least one micrometric component (1), said component comprises a structure (5, 6,10) created on or in a portion of a substrate (2), a cap (3) fixed to an area of the substrate in order to protect the structure, and a monitoring element (4,15) whose optical or electrical properties change in the presence of a reactive fluid. The monitoring element can be a copper layer (4) for optical control or a palladium resistor (15) for electric control. The micrometric component (1) is placed in an enclosure which is then hermetically closed. Said enclosure is filled with pressurized reactor fluid i.e. oxygen for optical control and hydrogen for electric control. The component inside the enclosure is subjected to a pressure of more than 10 bars of the reactive fluid during a set period of time and subjected to thermal activation ($T > 100^{\circ}C$) or optical activation (A < 500 nm). After said period, it is possible to determine the hermeticity of the cavity (14) by optical or electrical control of the monitoring element (4, 15).

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